



Docket No.: M4065.0227/P227 (PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

TECHLOLDEY CENTER 2800

In re Patent Application of: Tongbi Jiang, et al.

Application No.: 09/652,216

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Filed: August 30, 2000

For: METHOD AND APPARATUS FOR

REDUCING SUBSTRATE BIAS VOLTAGE

DROP

Examiner: E. Pert

Group Art Unit: 2813

RESPONSE TO RESTRICTON REQUIREMENT

Commissioner for Patents Washington, DC 20231

Dear Sir:

In response to the restriction requirement mailed October 18, 2001, applicant hereby elects claims 1-30 and 66-99 for continued examination, without traverse.

Applicant solicits issuance of claims 1-30 and 66-99.

Dated: November 7, 2001

Respectfully submitted

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